

1 **Growth of highly-oriented crystalline α -Fe/AlN/Fe₃N trilayer structures on**
2 **Si(111) substrates by molecular beam epitaxy**

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10
11 **Abstract**

12 We have realized highly-oriented nitride-based α -Fe/AlN/Fe₃N ferromagnetic hybrid
13 structures on Si(111) substrates by molecular beam epitaxy using AlN/SiC intermediate layers.

14 A two-step hysteresis loop, typically observed in magnetic tunneling junctions, was clearly
15 observed in magnetization versus magnetic field measurements. This result indicates the
16 formation of ferromagnetic α -Fe and Fe₃N layers separated by 8-nm-thick AlN layers over
17 approximately 1cm² areas, and also shows the difference in coercive field between the two
18 ferromagnetic layers.

21 **Keywords:** B3. magnetic tunnel junction; B2. Fe₃N; B2. α-Fe; B2. AlN; A3. MBE; A1.

22 SQUID

23 **1. Introduction**

24 Spintronics, a new research field of electronics based on the combination of magnetic
25 and semiconducting materials, has been attracting much attention. In particular, the tunnel
26 magnetoresistance (TMR) effect in magnetic tunnel junctions (MTJs), which consist of two
27 ferromagnetic layers separated by an insulating layer, has been extensively studied [1,2].
28 Magnetoresistive random-access memory (MRAM) is a device which utilizes the TMR effect
29 [3]. An MRAM is a nonvolatile memory, and is also believed to have high integrity in a
30 dynamic random-access memory (DRAM) as well as high-speed operation in a static
31 random-access memory (SRAM). To achieve a Gbit-scale MRAM, TMR ratios exceeding
32 150 % and output voltages over 190 mV are required [4]. One way to overcome these
33 difficulties is to grow crystalline MTJs, in which coherent electron tunneling without spin
34 scattering can be expected [5,6]. Giant TMR ratios have been achieved in MTJs consisting of
35 an MgO barrier layer and Fe-Co ferromagnetic layers [7], and further efforts have been made
36 in this material system [8]. We have been looking for other ferromagnetic and semiconducting
37 materials, and in particular, have been paying attention to nitride-based materials. Iron nitrides
38 are very interesting due to their special features such as high hardness, chemical inertness, and
39 high electrical conductivity [9-13]. Among them, ferromagnetic Fe₃N, Fe₄N and Fe₁₆N₂ have
40 been extensively studied for application in high-density magnetic recording heads and media
41 [14,15]. Very recently, Kokado *et al.* have predicted highly spin-polarized transport in Fe₄N

42 [16]. On the other hand, nitride semiconductors such as GaN and AlN are very important
43 materials for future electron and optical devices. They also possess high hardness and
44 chemical inertness. However, there have been no reports so far on the epitaxial growth of
45 ferromagnetic iron-nitrides on Si substrates, and nitride-based MTJs. We have succeeded in
46 the epitaxial growth of *c*-axis-oriented hexagonal Fe₃N films on Si(111) substrates by
47 molecular beam epitaxy (MBE) using AlN/3C-SiC intermediate layers [17,18]. It was found
48 that the AlN layers work as a template for Fe₃N overlayers, and that the AlN epitaxial layers
49 are likely to form on 3C-SiC.

50 In this paper, we report on the formation of highly-oriented nitride-based crystalline
51 α -Fe/AlN/Fe₃N trilayer structures on Si substrates by MBE for the first time. The magnetic
52 properties of the films were also discussed.

53

54 **2. Experimental procedure**

55 Prior to the formation of α -Fe/AlN/Fe₃N trilayer structures, the growth conditions of
56 highly-oriented α -Fe films on AlN layers were optimized using Si(111) substrates covered
57 with AlN/3C-SiC layers as follows. First, approximately 3-nm-thick 3C-SiC buffer layers
58 were grown through the carbonization of the Si surface using cracked C₃H₈ at 900°C [19,20].
59 Then, 10-nm-thick *c*-axis-orientated AlN layers were grown at 900°C using
60 di-methyl-aluminum hydride (DMAH) as an Al source and NH₃ as a N source [21]. After that,

61 40-nm-thick α -Fe layers were grown at several different temperatures using
62 iron-pentacarbony ($\text{Fe}(\text{CO})_5$) as an Fe source. For comparison, the formation of α -Fe films
63 was also tried directly on Si(111) substrates or Si substrates capped with 3C-SiC layers in the
64 same manner.

65 The formation of α -Fe/AlN/ Fe_3N trilayer structure was performed as follows. First,
66 30-nm-thick Fe_3N ferromagnetic layers were grown epitaxially on AlN/3C-SiC intermediate
67 layers by MBE. The detailed growth conditions were reported in our previous papers [16,17].
68 Then, 8-nm-thick AlN barrier layers were grown by an RF magnetron sputtering method at
69 100°C . The AlN layers were formed by sputtering an Al target in the mixture of Ar and N_2
70 atmosphere. The formation of (0001)-oriented AlN layer by this method was confirmed by
71 X-ray diffraction (XRD) not for the 8-nm-thick AlN but for much thicker AlN layers. The
72 deposition rate of AlN is approximately 6.6 nm/min, and the thickness of the AlN barrier layer
73 was thus determined using this deposition rate. Finally, 40-nm-thick α -Fe layers were grown
74 at 350°C .

75 The crystallinity of the grown layers was characterized by reflection high-energy
76 electron diffraction (RHEED) and XRD. All the RHEED patterns were taken from the [1-10]
77 azimuth of Si. Surface morphology was observed by atomic force microscopy (AFM). A
78 superconducting quantum interference device (SQUID) magnetometer was used to measure
79 the magnetic properties of the samples.

80

81 **3. Result and discussions**

82 *3.1 Formation of α -Fe on AlN*

83 Figures 1(a) and 1(b) show RHEED patterns of the 3C-SiC and AlN layers,
84 respectively. Figures 1 (c) -1(f) show RHEED patterns of α -Fe layers grown at different
85 temperatures on the AlN/3C-SiC intermediate layers. The streaky RHEED patterns were
86 observed for 3C-SiC and AlN layers as shown in Figs. 1(a) and 1(b). In contrast, the ring
87 pattern was observed after the supply of $\text{Fe}(\text{CO})_5$ at low temperatures as shown in Figs. 1(c)
88 and 1(d). With increasing the growth temperature, the diffraction spots appeared as shown in
89 Figs. 1(e) and 1(f). These results indicate that the crystallinity of α -Fe layers was improved
90 when the growth temperature was raised. Figure 2 shows θ -2 θ XRD patterns of these samples.
91 The diffraction peak of only α -Fe (110) was observed when the growth temperature becomes
92 equal to or higher than 300°C, indicating that highly (110)-oriented α -Fe was formed. The
93 diffraction spots observed in Figs. 1(e) and 1(f) were composed of two sets of diffraction
94 patterns of α -Fe, open and closed circles, as shown in Fig. 3(a). These patterns are thought to
95 be due to three possible epitaxial variants for (110)-oriented α -Fe layers on AlN(0001) as
96 shown in Figs. 3(b)-3(d). The diffraction spots denoted by closed circles in Fig. 3(a) can be
97 explained by α -Fe layers with the relationship as shown in Figs. 3(b) and 3(c). On the other
98 hand, the diffraction spots denoted by open circles are attributed to α -Fe layers as shown in

99 Fig. 3(d).

100 We also tried to form highly-oriented α -Fe layers directly on Si(111) substrates for
101 comparison; however, the Fe reacted with Si and thereby iron silicides such as FeSi, β -FeSi₂
102 and α -FeSi₂ were formed in spite of α -Fe layers. Highly-oriented α -Fe layers were difficult to
103 form even on 3C-SiC layers as shown in Fig. 4. Figure 4 shows the θ -2 θ XRD patterns after
104 the supply of Fe(CO)₅ onto the 3C-SiC layers at various temperatures. The diffraction peak of
105 α -Fe could hardly be confirmed. When the deposition temperature was 275°C, the diffraction
106 peak of α -Fe(110) was observed; however, the peak intensity was very small. On the basis of
107 these results, it can be said that the introduction of AlN layers is a very effective way to form
108 highly-oriented α -Fe layers on Si.

109

110 3.2 Formation of α -Fe/AlN/Fe₃N trilayer structure

Next, Next, we tried to form α -Fe(40 nm)/AlN(8 nm)/Fe₃N(30 nm) trilayer structure.
112 Figures 5(a), 5(b) and 5(c) show RHEED patterns observed after the growth of Fe₃N, AlN and
113 α -Fe layers, respectively. The diffraction spots of *c*-axis-oriented hexagonal Fe₃N were
114 observed as shown in Fig. 5(a), indicating that the monocrystalline Fe₃N was formed. The
115 root-mean-square (rms) roughness value of the Fe₃N measured by AFM was 6.1 nm. The
116 thickness of the Fe₃N layer was approximately 30 nm. Thus, the surface of the Fe₃N is not
117 smooth, and further studies are necessary to obtain a smooth surface of Fe₃N. The thickness of

118 the AlN barrier layer was therefore determined to be thick enough (8 nm) to separate the Fe₃N
119 layer from α -Fe overlayers in this work. The crystallinity of this AlN barrier layer is not good
120 enough compared to that formed at 900°C shown in Fig. 1(b). We think that this is due to the
121 low temperature formation of AlN layers. Figure 6 shows the θ -2 θ XRD pattern of samples
122 after the formation of (a) Fe₃N layers and (b) trilayer structure. We can see the diffraction
123 peaks of AlN(0002) as well as Fe(110) in Fig. 6(b). The RHEED pattern of the α -Fe layer
124 shown in Fig. 5(c) is a ring pattern. This means that a polycrystalline α -Fe layer was grown.
125 The difference in RHEED pattern of α -Fe between Figs. 1(e, f) and Fig. 5(c) is attributed to
126 the difference in crystallinity of AlN underlayers.

127 The two solid lines in Fig. 7 show the magnetization versus magnetic field (M - H)
128 curves measured at 280 K after the growth of the Fe₃N layer and the trilayer structure. The
129 external H was applied parallel to the sample surface. We can see a clear two-step structure
130 for the trilayer structure, which is usually observed in MTJs. This is attributed to the
131 difference in coercive field, H_c , between the α -Fe and Fe₃N ferromagnetic layers, showing
132 the successful formation of ferromagnetic α -Fe and Fe₃N layers separated by the AlN layer
133 over the entire sample areas of approximately 1cm². This M - H curve is the sum of the M - H
134 curve of the α -Fe (broken line) and that of the Fe₃N (dotted line) in the trilayer structure. The
135 saturation magnetization, M_s , of α -Fe, which is 1737 emu/cm³ [13], explains the broken line
136 well. The M_s value for the Fe₃N layer in the dotted line also agrees well with that for the Fe₃N

137 in the solid line. However, the H_c value in the Fe_3N decreased from 150 Oe in the solid line to
138 45 Oe in the dotted line. We think that this is because the crystallinity of the Fe_3N layer
139 changed during the formation of the AlN and subsequent α -Fe overlayers. The electrical
140 properties of the trilayer structure are now under investigation. We think that the formation of
141 the hybrid structures presented in this work is an important step toward realizing nitride-based
142 MTJs.

143

144 **4. Conclusion**

145 Highly (110)-oriented α -Fe layers were formed on AlN layers at temperatures equal
146 to or higher than 300°C using $\text{Fe}(\text{CO})_5$ as an Fe source. Using this growth condition, we next
147 formed crystalline α -Fe(40 nm)/AlN(8 nm)/ Fe_3N (30 nm) trilayer structures on Si(111)
148 substrates using the AlN/SiC intermediate layers, where the α -Fe was (110)-oriented and the
149 Fe_3N was c -axis-oriented. In the M - H measurements, a two-step hysteresis loop was clearly
150 observed at 280 K, meaning that the two ferromagnetic layers were separated by the AlN
151 layer.

152

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157 **References**

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159 [1] T. Miyazaki, N. Tezuka, *J. Magn. Magn. Mater.* **139** (1995) L231.

160 [2] J. S. Moodera, L. R. Kinder, T. W. Wong, R. Merservey, *Phys. Rev. Lett.* **74** (1995) 3273.

161 [3] S. A. Wolf, D. D. Awschalom, R. A. Buhrman, J. M. Daughton, S. Von Molnár, M. L.

162 Roukes, A. Y. Chchelkanova, D. M. Treger, *Science* **294** (2001) 1488.

163 [4] S. Yuasa, A. Fukushima, T. Nagahama, K. Ando, Y. Suzuki, *Jpn. J. Appl. Phys., Part 2* **43**

164 (2004) L588.

165 [5] J. Mathon, A. Umerski, *Phys. Rev.* **B 63** (2001) 220403R.

166 [6] S. Yuasa, T. Nagahama, A. Fukushima, Y. Suzuki, K. Ando, *Nat. Mater.* **3** (2004) 868.

167 [7] S. Yuasa, A. Fukushima, H. Kubota, Y. Suzuki, K. Ando, *Appl. Phys. Lett.* **89** (2006)

168 082512.

169 [8] S. Ikeda, J Hayakawa, Y. M. Lee, F. Matsukura, H. Ohno, *J. Magn. Magn. Mater., Part 3*

170 **310** (2007) 1937.

171 [9] N. Takahashi, Y. Toda, T. Nakamura, T. Fujii, *Jpn. J. Appl. Phys., Part 1* **38** (1999) 6031.

172 [10] K. Tagawa, E. Kita, A. Tasaki, *Jpn. J. Appl. Phys., Part 1* **21**(1982) 1596.

173 [11] T. Takahashi, N. Takahashi, T. Nakamura, T. Kato, K. Furukawa, G. M. Smith, P. C. Riedi,

174 *Solid State Sci.* **6** (2004) 97.

175 [12] E.H. Du Marchie, Van Voorthuysen, N. C. Chechenin, D.O. Boerma, *Metallurgical &*

176 Materials Transactions **33A** (2002) 2593.

177 [13] M. Mekata, H. Yoshimura, H. Takai, J. Phys. Soc. Jpn. **33** (1972) 62.

178 [14] H. Takahashi, M. Komuro, M. Hiratani, M. Igarashi, Y. Sugita, J. Appl. Phys. **84** (1998)

179 1493.

180 [15] T. K. Kim, M. Takahashi, Appl. Phys. Lett. **20** (1972) 492.

181 [16] S. Kokado, N. Fujima, K. Harigawa, H. Shimizu, A. Sakuma, Phys. Rev. **B73** (2006)

182 172410.

183 [17] K. Yamaguchi, T. Yui, K. Yamaki, I. Takeya, K. Kadowaki, T. Suemasu, J. Crystal

184 Growth **301**(2007) 597.

185 [18] K. Yamaguchi, T. Yui, Y. Ichikawa, K. Yamaki, I. Takeya, K. Kadowaki, T. Suemasu, Jpn.

186 J. Appl. Phys., Part 2 **45** (2006) L705.

187 [19] T. Hatayama, T. Fuyuki, H. Matsunami, Jpn. J. Appl. Phys., Part 2 **34** (1995) L1117.

188 [20] T. Yoshinobu, H. Mitsui, Y. Tarui, T. Fuyuki, H. Matsunami, Jpn. J. Appl. Phys., Part 2 **31**

189 (1992) L1580.

190 [21] K. Yamaguchi, H. Tomioka, R. Souda, T. Suemasu, F. Hasegawa, Jpn. J. Appl. Phys., Part

191 2 **43** (2004) L151.

192

193 **Figure captions**

194

195 Figure 1 RHEED patterns taken after the growth of (a) 3C-SiC and (b) AlN layers. (c),
196 (d), (e) and (f) are RHEED patterns of α -Fe layers grown at 250 °C, 300 °C, 350 °C and 400
197 °C, respectively, on the 3C-SiC/AlN intermediate layers.

198

199 Figure 2 θ -2 θ XRD patterns of α -Fe layers grown on AlN/3C-SiC intermediate layers
200 at various temperatures.

201

202 Figure 3 (a) RHEED pattern of the (110)-oriented α -Fe layers grown at 400°C. The
203 closed circles and open ones correspond to those obtained from α -Fe layers with the
204 relationship of (b,c) and (d) on AlN(0001), respectively. The squares are diffraction spots
205 obtained from all the three kinds of epitaxial variants.

206

207 Figure 4 θ -2 θ XRD patterns taken after the supply of Fe(CO)₅ on 3C-SiC layers at
208 various temperatures.

209

210 Figure 5 RHEED patterns of the (a) Fe₃N, (b) AlN and (c) α -Fe layers in the trilayer
211 structures.

212 Figure 6 θ -2 θ XRD patterns after the formation of (a) Fe₃N layers and (b) AlN and
213 subsequent α -Fe layers.

214

215 Figure7 M - H curves measured at 280 K with H parallel to the sample plane. The
216 solid lines are the M - H curves measured after the growth of the Fe₃N layers and trilayer
217 structures. The broken and dotted lines are thought to correspond to the M - H curves of α -Fe
218 and Fe₃N layers in the trilayer structures, respectively.